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MEMC 99-0900 (2632)
PATENT

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Lipka
B.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Robert H. Fuerhoff et al.

Serial No. 09/502,340

Filed February 10, 2000

For METHOD AND APPARATUS FOR CONTROLLING DIAMETER OF A SILICON
CRYSTAL IN A LOCKED SEED LIFT GROWTH PROCESS

July 13, 2000

TO THE COMMISSIONER OF PATENTS AND TRADEMARKS,

SIR:

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

In accordance with 37 C.F.R. 1.97 and 1.98 and MPEP 609, and in compliance with the duty of disclosure set forth in 37 C.F.R. 1.56, applicants submit copies of the references listed on the attached PTO Form 1449 (modified) for consideration by the Patent and Trademark Office in the above-entitled application and to be made of record herein. I certify that each item contained in this statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

Respectfully submitted,

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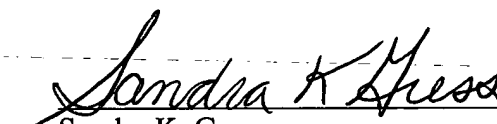
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CERTIFICATE OF MAILING

I certify that this SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT and attached PTO Form 1449 in the application of Robert H. Fuerhoff et al, Serial No. 09/502,340, filed February 10, 2000 is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on this 13th day of July, 2000.


Sandra K. Gress

RMBskg
*Attachments